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1 18 10 15 TEMENT BY APPLICANT				First Named Inventor	Yongli HUANG	
				Art Unit	3736	
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E T & JATES	1	of	2	Attorney Docket Number	33683/AJT (468330-01807)	

	U.S. PATENT DOCUMENTS								
Examiner thitiats*	Cite No.	U.S. Patent Document Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figure Appear				
	A1	6,144,481	11-07-2000	Kowarz et al.					
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	FOREIGN PATENT DOCUMENTS									
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				Art Unit	3736		
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Sheet	2	of	2	Attorney Docket Number	33683/AJT (468330-01807)		

		NON PATENT LITERATURE DOCUMENTS							
Examiner Initials*	Cite No.1	include name of the author (in CAPITAL LETTERS), litle of the article (when appropriate), litle of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁴						
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² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04.

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16 if possible.

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